

Electronic Patent Application Fee Transmittal

Application Number:	10516455			
Filing Date:	03-Dec-2004			
Title of Invention:	Method and device for substrate etching with very high power inductively coupled plasma			
First Named Inventor/Applicant Name:	Michel Puech			
Filer:	Michael R. Dzwonczyk/Lynette Mansfield			
Attorney Docket Number:	Q84452			
Filed as Large Entity				
U.S. National Stage under 35 USC 371 Filing Fees				
Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Basic Filing:				
Pages:				
Claims:				
Miscellaneous-Filing:				
Petition:				
Patent-Appeals-and-Interference:				
Post-Allowance-and-Post-Issuance:				
Extension-of-Time:				
Extension - 3 months with \$0 paid	1253	1	1050	1050

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Miscellaneous:				
Total in USD (\$)				1050